

Rapid prototyping of silicon structures by aid of laser and abrasive-jet machining

Kruusing, Arvi; Leppävuori, Seppo; Uusimäki, Antti; Uusimäki, M. Design, Test and Microfabrication of MEMS and MOEMS : 30 March-1 April, 1999, Paris, France 1999 / p. 870-878 : ill